



# Internal Project Application

There is a fee waiver available for non-proprietary internal research that supports the NIST mission of promoting U.S. innovation and industrial competitiveness by advancing measurement science, standards, and technology in ways that enhance economic security and improve our quality of life

***Non-proprietary research is not confidential, public access is permitted to the resulting data, and the research in general will be published with an acknowledgment to CNST. To be eligible for the fee waiver, the proposal must be non-proprietary and support the CNST mission if the PI is not a NIST staff member.***

Do you wish to apply for partial the fee waiver?	Yes	No
Is the research non-proprietary	Yes	No

***Please clearly answer the following:***

**1. Describe the long-term goal of your research project.**

**2. What is the expected significance of this project and its impact on measurement methods for nanotechnology?**

**3. Which aspects of this project require Nanofab capabilities?**

**Which tools do you plan to use?**

Photolithography

Dry etch

Furnaces

Metal Deposition

Inspection

Wet chemistry

Wafer saw/wire bonder

Imprint lithography

Focused ion beam

Electron beam lithography

4. Describe in some detail the work you intend to conduct in the Nanofab. Specify materials and chemicals you will be using.

5. Describe any previous results, information, or publications which can be provided to support the work intended to be completed in the Nanofab

Please attach a copy of any referenced publications to this application

Upon acceptance of your application, please provide billing information. You may choose to

**Do not write below this line – For CNST use only**

*Proposal #* \_\_\_\_\_ *Date Received:* \_\_\_\_\_ *Date Approved:* \_\_\_\_\_